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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
TAKAHIRO HORIGUCHI ET AL : EXAMINER: KACKAR, RAM N.
SERIAL NO: 09/855,493 :
FILED: MAY 16, 2001 : GROUP ART UNIT: 1763
FOR: SINGLE-SUBSTRATE-PROCESSING:
APPARATUS FOR SEMICONDUCTOR

AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Official Action dated August 1, 2002, please amend the above-identified patent application as follows:

IN THE SPECIFICATION

Please amend the specification to read as shown below:¹

Please amend the paragraph on page 10, beginning at line 14, to read as shown below:

The casing 2a of the process chamber 2 is constituted of upper and lower casing parts, ^A which are detachably joined at a position close to the middle in the vertical direction. The upper casing part, in which the worktable 3 is disposed, has a diameter larger than that of the

¹The changes to the claims are shown using underscoring and bracketing in the marked-up copy attached herewith.